

AMENDMENTS TO THE CLAIMS

1. (Original) A multi-stage baking apparatus for a plasma display comprising a baking furnace for performing heat treatment to substrates while conveying the substrates, wherein plural stages of conveying means for conveying the substrates are provided, and the conveying means adjacent in an up and down direction are divided with heat insulating partitions provided between them so as to have a multi-stage structure in the baking furnace, and heating means are provided appropriately to the heat insulating partitions within the baking furnace, and a heating area, a keeping area and a cooling area are provided in order in a traveling direction of the conveying means within each furnace of each of the multiple stages.
2. (Original) The multi-stage baking apparatus for a plasma display panel as claimed in claim 1, wherein the heating means in the baking furnace may be so configured as to be able to control a heating amount separately, or configured as to control a heating amount of each temperature zone provided in a conveying direction of the substrates.
3. (Currently Amended) The multi-stage baking apparatus for a plasma display panel as claimed in claim 1~~or 2~~, wherein the heating means is an electric heater.
4. (Currently Amended) The multi-stage baking apparatus for a plasma display panel as claimed in claim 1~~or 2~~, wherein a return conveyer is provided under the conveying means in multiple stages for conveying the substrates.